

Electron Beam Evaporation System

Model: SA-VKE1100/E1500

SA-VKE1100 and SA-VKE1500 are mass-production electron beam evaporation platforms. Equipped with a wide uniform coating region, they deliver consistent stable operation, complete automated control and low maintenance costs, perfectly catering to high-throughput evaporation processes for oversized substrates and workpieces.



Feature

- Low cost
- Lift-off
- Co-deposition
- High evaporation rate

Application

- Laser
- R&D
- Integrated circuit
- MEMS

Specifications:

Parameter	Descriptions
Number of Crucibles	8(max.)
Power Supply	10kW(max.)
Film thickness monitoring	Crystal oscillator controller
Ion Source	RF & Kaufman & Hall ion source
Fixture types	Dome & Knudsen & Planetary
Pumping System	Cryopump / magnetically levitated turbo-molecular pump + Dry mechanical pump
Coating Uniformity	±2%
Coating Repeatability	±2%
Uniform Deposition Area	Ø300 mm(max.)
Ultimate Vacuum	2E-5Pa
Vacuum Measurement	Full-range vacuum gauge
Temperature Control Range	RT~300℃
Space Requirements(L×W×H,m)	4.05×3.9×2.8

Principle:

